

Supporting Information

Edge sites on TiO₂ as aKey Type of Photocatalytically Active Site

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EXPERIMENTAL SECTION

Experimental section. The experiments were performed in a stainless-steel ultrahigh vacuum (UHV) system equipped with differentially-pumped thermal desorption spectroscopy (TPD), low energy electron diffraction (LEED), X-ray photoelectron spectroscopy (XPS), and ultraviolet photoelectron spectroscopy (UPS). The base pressure for the sample chamber is $1-2 \times 10^{-10}$ Torr. A rutile $\text{TiO}_2(110)$ single crystal ($8 \text{ mm} \times 8 \text{ mm} \times 1 \text{ mm}$) purchased from MaTeck was mounted onto a Ta support plate ($8 \text{ mm} \times 8 \text{ mm} \times 1 \text{ mm}$) by a mixture of high-temperature alumina-based inorganic adhesive (Aremco 503) and graphite powder (99.9995%, Alfa Aesar China Co., Ltd.). Via two Ta wires spot-welded to its backside, the sample was resistively heated and cooled. The temperature was controlled and measured between 110 and 1273 K by a chromel-alumel thermocouple spot-welded to the backside of the sample plate. The rutile $\text{TiO}_2(110)$ surface was first cleaned by repeated cycles of Ar ion sputtering at 1 kV for 10 min, annealing in oxygen at 750 K for 10 min, and vacuum annealing at 1000 K for 10 min until XPS detected no contaminants other than argon. The rutile $\text{TiO}_2(110)$ surface was further cleaned before experiments by repeated cycles of annealing in oxygen at 700 K for 30 min and vacuum annealing at 1000 K for 10 min until XPS did not detect the contaminants of argon. CO (>99.99%), CO_2 (>99.999%), and O_2 (>99.999%), purchased from Nanjing ShangYuan Industry Factory, were used as received and were checked their purities by QMS before experiments. All exposures in the experiments were reported in Langmuir ($1 \text{ L} = 1.0 \times 10^{-6}$ Torr·s) without corrections for the gauge sensitivity. During TPD measurements, the TiO_2 sample was positioned $\sim 1 \text{ mm}$ away from a collecting tube of a differential-pumped QMS and the heating rate is 2 K/s. XPS spectra were recorded by using Mg $K\alpha$ radiation ($h\nu = 1253.6 \text{ eV}$) with a pass energy of 20 eV. The Ti 2p XPS spectra were peak-fitted with the XPSPEAK software (Version 4.1) using a Shirley-type background.

Hg irradiation was accomplished by using a 100 W high-pressure Hg arc lamp (Oriel 6281), which provides a pressure-broadened emission spectrum in the UV light region from gaseous Hg. The light irradiance of this source is found to be decreased rapidly and is only 0.05 mW/m^2 for the 200 nm light at a distance of 0.5 m when the light wavelength is below 250 nm. Thus the light absorption by methanol/ TiO_2 in the UV light region below 200 nm can be neglected under our experimental condition. The IR portion of the emission spectrum was removed by a water filter. The Hg light was focused onto the tip of a single strand, 0.6 mm diameter fused silica fiber-optic cable directed the light through UHV-compatible feedthrough onto the rutile $\text{TiO}_2(110)$ surface without exposure to extraneous surfaces. The Hg light resulted in the rising of crystal temperature no more than 0.5 K on $\text{TiO}_2(110)$ at 110 K.

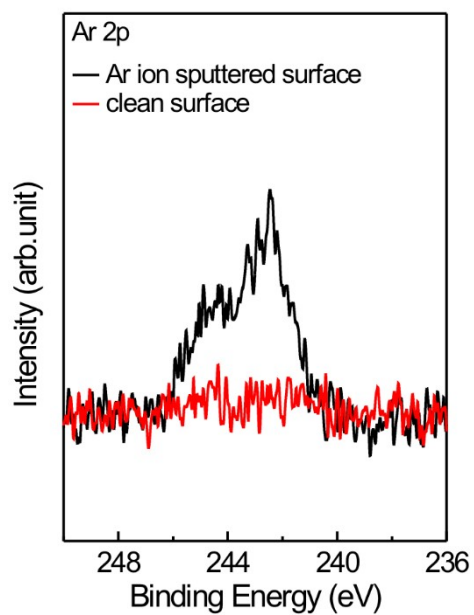


Figure S1. Ar 2p XPS spectra of argon ion sputtered and clean TiO₂(110) surfaces, proving the residual argon was introduced into TiO₂(110) surface after argon-ion bombardment.

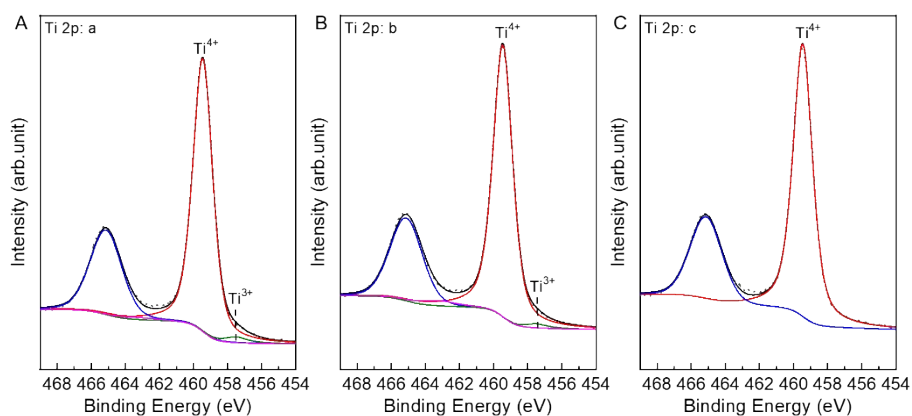


Figure S2. Peak-fitted Ti 2p XPS spectra of r-TiO₂(110)-1000 K, r-TiO₂(110)-800 K, and o-TiO₂(110) surfaces. The Ti³⁺ feature is shown in the Ti 2p XPS spectra of r-TiO₂(110)-1000 K and r-TiO₂(110)-800 K surfaces. Meanwhile, the o-TiO₂(110) surface does not exhibit the Ti³⁺ feature.

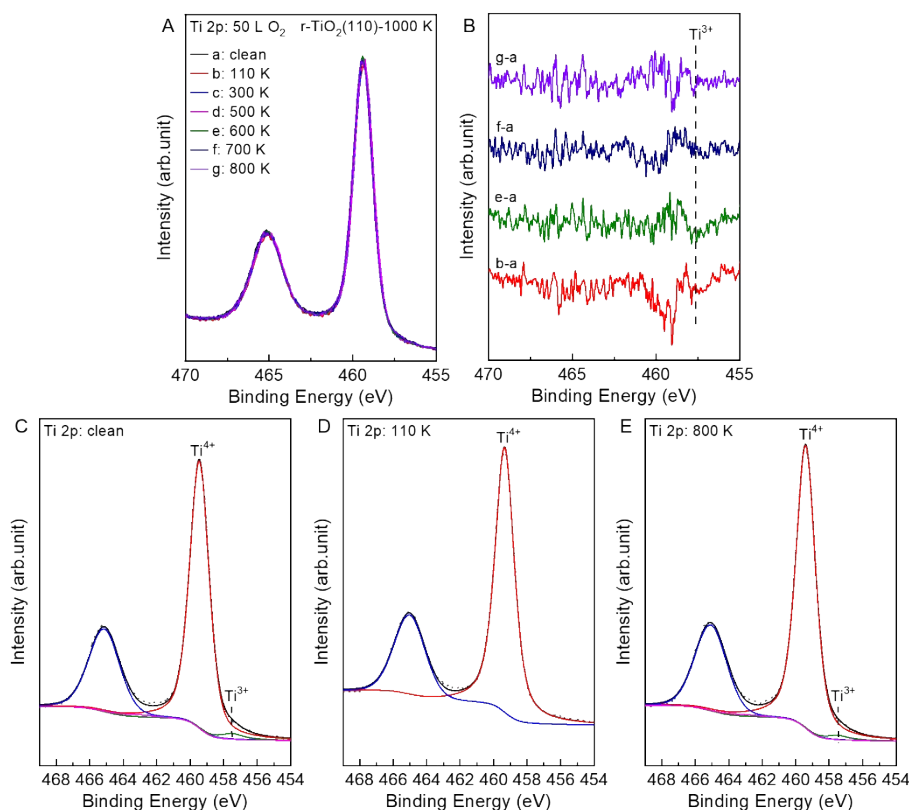


Figure S3. (A) Ti 2p XPS spectra, (B) corresponding difference spectra and (C-E) Peak-fitted Ti 2p XPS spectra after an exposure of 50 L of O₂ on the r-TiO₂(110)-1000 K surface at 110 K followed by annealing at elevated temperatures. In the difference spectra, the negative peak results from the reduction of Ti⁴⁺ 2p and Ti³⁺ 2p components after an exposure of 50 L of O₂ on the r-TiO₂(110)-1000 K surface at 110 K. The negative Ti³⁺ shoulder feature does not vary upon annealing up to 600 K, and then decreases upon annealing at 700 K and further at 800 K, arising from regeneration of Ti³⁺ by high-temperature annealing. In the peak-fitted spectra, the Ti³⁺ feature disappeared after an exposure of 50 L of O₂ on the r-TiO₂(110)-1000 K surface at 110 K while we observed the Ti³⁺ feature again on the surface followed by annealing at 800 K.

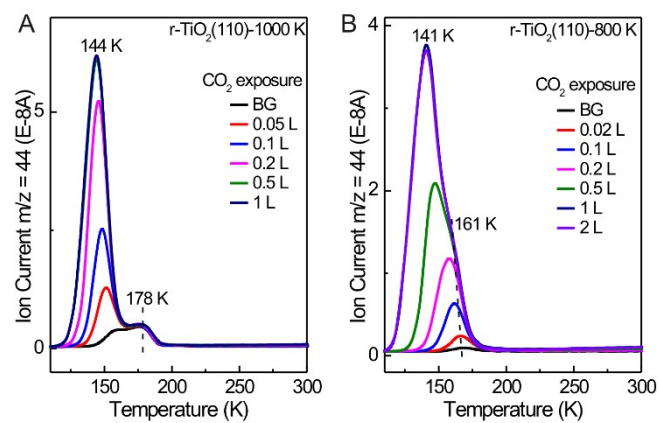


Figure S4. TPD spectra of (A) r-TiO₂(110)-1000 K and (B) r-TiO₂(110)-800 K surfaces with various CO₂ coverages at 110 K.

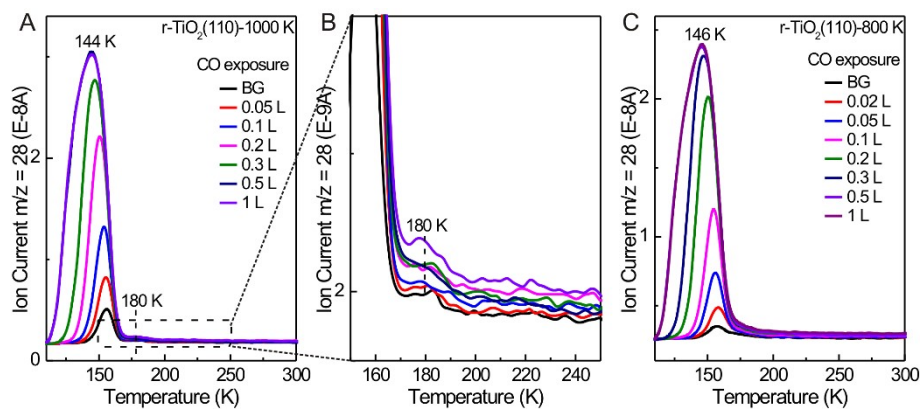


Figure S5. (A) Normal and (B) amplifying TPD spectra of r-TiO₂(110)-1000 K surface, and TPD spectra of (C) r-TiO₂(110)-800 K surface with various CO coverages at 110 K.

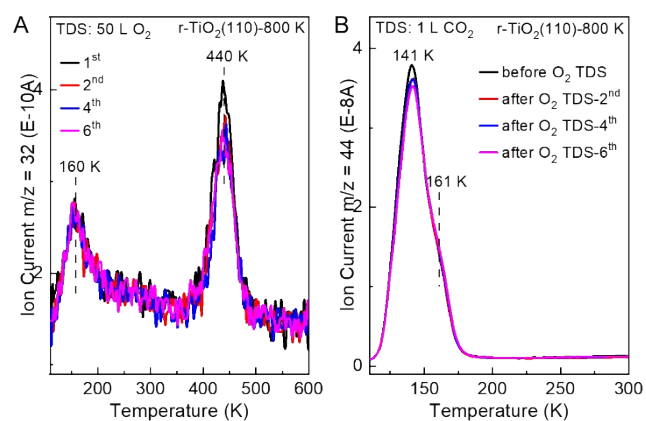


Figure S6. (A) O₂ TPD spectra of r-TiO₂(110)-800 K surface with repeated exposures of 50 L O₂ at 110 K. (B) CO₂ TPD spectra of r-TiO₂(110)-800 K surface exposed to saturated CO₂ before and after O₂ TPD experiments at 110 K.

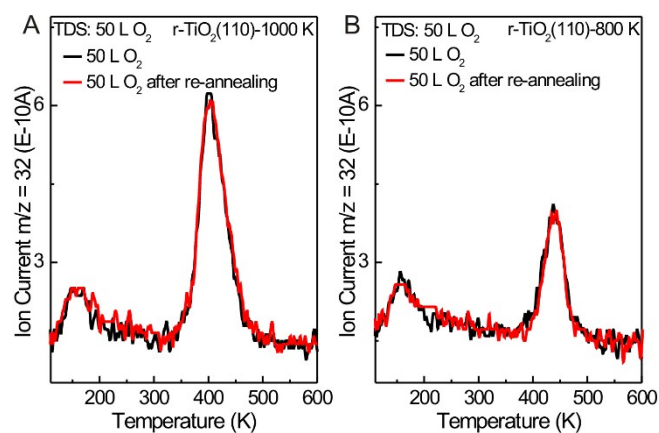


Figure S7. TPD spectra of (A) r-TiO₂(110)-1000 K and (B) r-TiO₂(110)-800 K surfaces exposed to 50 L O₂ at 110 K after a re-annealing of the surface, proving the reproducibility of our method used to prepare both r-TiO₂(110)-1000 K and r-TiO₂(110)-800 K surfaces.

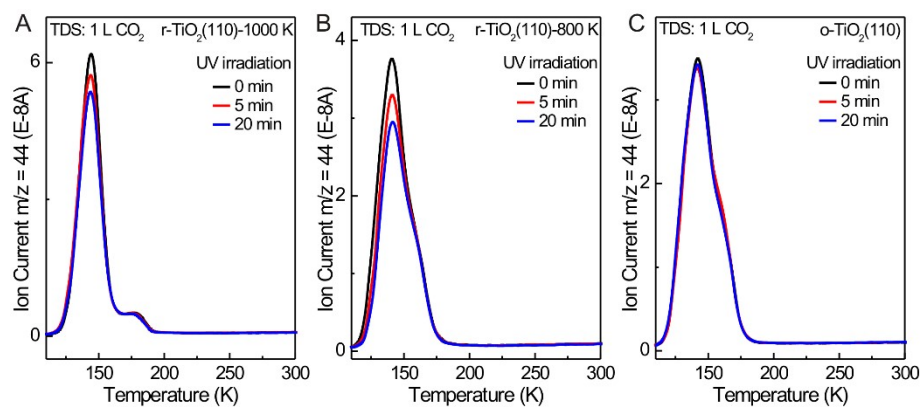


Figure S8. TPD spectra of (A) r- $\text{TiO}_2(110)$ -1000 K, (B) r- $\text{TiO}_2(110)$ -800 K, and (C) o- $\text{TiO}_2(110)$ surfaces exposed to 1 L CO_2 with UV light illumination for various times at 110 K.

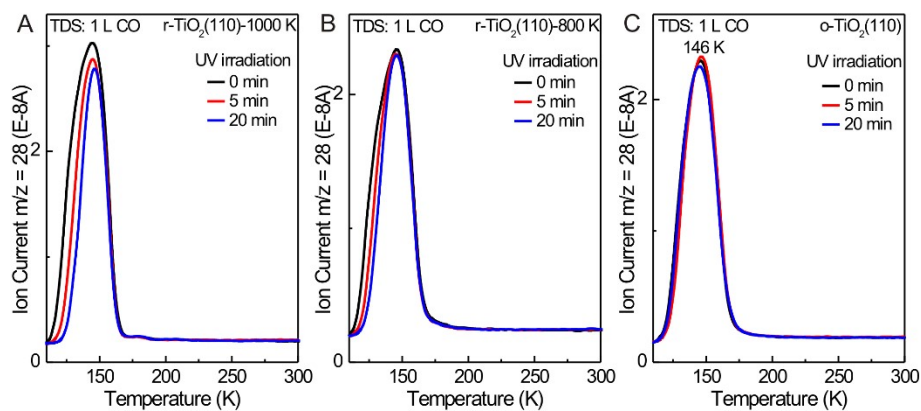


Figure S9. TPD spectra of (A) r-TiO₂(110)-1000 K, (B) r-TiO₂(110)-800 K, and (C) o-TiO₂(110) surfaces exposed to 1 L CO with UV light illumination for various times at 110 K.